Special Issue

Accelerometer and Magnetometer: From Fundamentals to Applications

Message from the Guest Editors

Accelerometers and magnetometers have been widely in consumer electronics, automobiles, precision manufacturing, defense, aerospace and geophysical applications. MEMS technology opens up the possibility to meet the requirements of Cost, Size, Weight and Power (CSWaP), and performance of those applications. Even though, those sensors still suffer scientific barriers towards those applications. Major challenges include but are not limited to: microfabrication processes, new materials, device design and optimization, interface circuits, signal processing and sensors fusions. In addition, new mechanisms which are promising to be implemented by micromachines, such as atomic, optical levitation and optomechanical technologies, are highly interested. This Special Issue calls for the original research papers and reviews with the state-of-the-art results in the relevant topics.

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